

Title of Invention

METHOD OF DEPOSITING METAL FILM AND METAL DEPOSITION CLUSTER TOOL INCLUDING SUPERCRITICAL DRYING/CLEANING MODULE

Application Number:

09/841800

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Confirmation Number:

6810

First Named Applicant:

Maximilian Biberger

Attorney Docket Number:

Search string:

(5807607 or 5847443 or 5872061 or 5893756 or 5896870 or 5904737 or 5992680 or 5994696 or 6001133 or 6005226 or 6037277 or 6063714 or 6099619 or 6100198 or 6128830 or 6140252 or 6171645 or 6200943 or 6216364 or 6224774 or 6228826 or 6232238 or 6232417 or

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Note: Applicant is not required to submit a paper copy of cited US Patent Documents

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Remarks

Note: Remarks are not for responding to an office action.

Non US Patent and Publication references shall be filed under a separate paper transmittal. The current electronic filing contains part 4 out of a total of 5 electronic filings. Fee has been paid in previous electronic filing.

Signature

Examiner Name	Date
C. Everkard	2-24-04

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ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Sectronic Version v18 Stylesheet Version v18.0

Title of Invention

METHOD OF DEPOSITING METAL FILM AND METAL-DEPOSITION CLUSTER TOOL INCLUDING SUPERCRITICAL DRYING/CLEANING MODULE

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Search string:

(5370741 or 5714299 or 5725987 or 5736425

or 5766367).pn.



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C. Kucharl	2-24-04



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Search string:

(6251250 or 6255732 or 6270531 or 6270948 or 6277753 or 6284558 or 6286231 or 6306564 or 6331487 or 6344243 or 6358673 or 6361696 or 6367491 or 6380105 or 6425956 or 6436824 or 6454945 or 6458494 or 6461967 or 6485895 or 6486078 or 6486282 or 6492090 or 6500605 or 6558475 or 6562146 or 20010019857 or 20010024247 or 20010041455 or 20010041458

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or 20020142595 or 20020150522 or

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Examiner Name	Date
C' Everhard	2-24-04

Translation

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Yes

Serial No.: 09/841,800 U.S. Department of Commerce Patent and Trademark Office FORM PTO-1449 (Modified) 1 8 2003 Attorney Docket No.: \$\$1-02001 INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use Several Streets If Necessary) Applicants: Maximilian A. Biberger et al. Group Art Unit: 2825 (37 CFR § 1.98(b)) FOREIGN PATENTS OR PUBLISHED FOREIGN PATENT APPLICATIONS Class Subclass Document Country / Patent Office **Publication Date** Number M 1/00 D 06 L ME DE 39 04 514 C2 08/23/90 Germany AA D 06 P 1/90 09/13/90 Germany AΒ DE 39 06 724 C2 D 06 L 3/00 DE 39 06 735 C2 09/06/90 Germany АC D 06 M 11/59 09/13/90 DE 39 06 737 A1 Germany AD D 06 L 1/00 ΑE DE 40 04 111 C2 08/23/90 Germany D 06 P 1/16 06/29/95 AF / DE 43 44 021 A1 Germany D 06 P 5/04 DE 44 29 470 A1 03/02/95 AG 1 Germany D 06 L 1/02 EPO AH EP 0 518 653 B1 12/16/92 7/50 CIID ΑI EP 0 620 270 A3 10/19/94 EPO D06F 43/00 EPO ĄJ EP 0 679 753 B1 11/02/95 D06G 1/00 EP 0,711 864 B1 05/15/96 **EPO** AK -JP 1-246835 10/02/89 HOIL 21/304 AL Japan H01L 21/56 JP 8-186140 07/16/96 AM Japan B08B 7/00 **PCT** AN WO 90/06189 06/14/90 WO 90/13675 11/15/90 **PCT** C22B 3/00 ΑO **PCT** D06B 5/16 AP -WO 93/14255 07/22/93 11/76 D06M WO 93/14259 07/22/93 PCT A0 PCT C08F 14/18 WO 93/20116 y 10/14/93 AR WO 96/27704 🔄 09/12/96 PCT D06L 1/00 AS 35/622 **PCT** C04B ΑT WO 00/73241 A1 12/07/00 B08B ΑU WO 02/09894 A2 02/07/02 PCT **PCT** H01L 21/00 WO 02/11191 A2 02/07/02 AVAW / WO 02/16051 A2 02/28/02 **PCT** B05D OTHER DOCUMENTS (Including Author, Title, Date, Relevant Pages, Place of Publication) "Porous Xerogel Films as Ultra-Low Permittivity Dielectrics for ULSI Interconnect Applications", Materials Research Society, pp. 463-469, AX a ΑY AZ '

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Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form

EXAMINER:

with next communication to applicant.

ORM PTO-1449 (Modified) U.S. Department of Commerce Patent and Trademark Office Serial No.: 09/841,800 Attorney Docket No.: SSI-02001 INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use Several Sheets If Necessary) Applicant: Maximilian A. Biberger et al. Group Art Unit: 2812 Filing Date: April 24, 2001 FOREIGN PATENTS OR PUBLISHED FOREIGN PATENT APPLICATIONS Translation Document Number Class Subclass **Publication Date** Country / Patent Office No Yes 21/3213 DE 198 60 084 Х HOI L 07/06/00 . Germany Х HOIL 21/306 02/04/98 EΡ ΑB EP 0 822 583 A2 х B 08 B 3/08 03/18/98 EP AC EP 0 829 312 A2 HOIL 21/302 х JP AD JP 2-209729 8/21/90 ΑE ΑF ΑĜ AΗ ΑĪ ΑJ ΑK ΑL ΑM AN ΑO ΑP AQ AR AS ΑŤ ΑU ΑV ΑW ΑX ΑY BA BB BC BD BE BF 2-24-09 verhast Date Considered:

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(2439689 or 4349415 or 4925790 or 5071485

or 5196134 or 5269850 or 5285352 or

5320742).pn.

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Remarks

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C. Jwerhart

2-24-04